Autosamdri®-931 Multi-Application CPD

2.50" Process Chamber, Cleanroom Version



- Multi-Application Critical Point Dryer for Cleanroom Use
- "Stasis Software" for Challenging Sample Types
- Winner of Microscopy Today Innovation Award
- Post Process Data Review
- HF Compatible Holders Included with System
- Program and Save Custom Recipes
- Made in U.S.A.

CLEANROOM MULTI-APPLICATION CPD Autosamdri®-931 with 2.50in Chamber (Cat. # 8787E)

FEATURES

- Cleanroom Material Fabricated Static Free Design
- Bright LCD Touchscreen Control
- Default "Automode" setting suitable for most wafer and die MEMS applications
- Process up to 5 substrates per process run (either Wafers or Die)
- HF Compatible Holders for 2" (50mm) diameter wafers and 10mm square die included with system
- Create and save custom Recipes exactly for your specific sample needs
- Easy View Placement of Micro Metering Valves with Vernier Handles
- · Slow Fill feature protects the most delicate samples
- Fast adiabatic chamber cooling (≈ 2 minutes from 25°C to 3°C)
- Maintenance Free Non-Mechanical Vortex Swirl[™] Purge Stirring
- External 0.5µm Post-Purge filter access for easy preventive maintenance
- External LCO₂ tank supply particulate filtration using 'Double T-Filter' design with 99.5%+ retention
- Internal filtration delivers filtered LCO₂ down to 0.08µm with 99.999+% retention directly into process chamber
- Internal SOTER[™] Condenser quietly separates waste alcohol and CO₂ while eliminating any freeze up or static discharge
- EZ top loading process chamber with LED illumination
- "Stasis Software" for drying GELS and other challenging sample types
- Post Process Previous Run Data Review
- All components meet CE, UL and/or U.S. Military specifications
- 2 year warranty on all parts and labor
- Made in U.S.A.

SPECIFICATIONS

- Cabinet: (W) 15.0" (38.0cm) x (H) 13.25" (33.5cm) x (D) 20" (50.8cm)
- System Set-Up Area Required: (W) 24" (61cm) x (D) 22" (56cm)

Chamber size:

2.50" ID x 1.25" Depth (63.50mm ID x 31.75mm Depth) - 100ml Volume

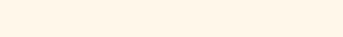
• Pressure Gauge Range: 0 to 2000 psi, Temperature Range - 30°C to 60°C

• 120V or 220V Models Available

STANDARD ACCESSORIES

- Flexible High-Pressure LCO₂ Supply Hose, 10ft (3.0m) Note: Other lengths available upon request up to 50ft (15m)
- HF Compatible Substrate Holders included: 2" (50mm) wafer holder as well as a 10mm square die holder for up 5 die
- Chamber Insert included that reduces LCO₂ consumption and reduces chamber ID from 2.50" down to 1.25"
- Double T-Filter Assembly (#8785-see insert picture) pre-installed onto the LCO₂ high-pressure hose. LCO₂ filtered twice thru 0.5µm filters prior to LCO₂ entering Autoamdri[®]-931 process chamber
- Static Free Exhaust Tubing
- Flow Meter supplied allows precise BLEED Exhaust Calibration
- Spare chamber O-rings (2), LED chamber lamp (1), and 5A slo-blow fuses (2)
- User Manual and Check-Out Data Sheet
- Installation Tool Kit
- Free Lifetime Technical Support

Please contact us for custom substrate holders

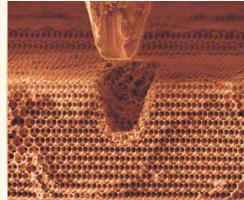




Released Cantilevers after Thermal Annealing Nicolas André Université Catholique de Louvain, Belgium



Double T-Filter Assembly (#8785) Pre-Installed onto High Pressure Hose



Inverse Opal Julia R. Greer / Greer Group Caltech / Materials Science and Mechanics

* U.S. patented (# 6,493,964) or patent pending. Note: Actual delivered model or accessories may vary slightly as advancements are integrated into systems

